IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **NISHIUCHI, et al.**

Group Art Unit: **1763**

Serial No.: **10/615,381**

Examiner: **Richard R. BUEKER**

Filed: **July 9, 2003**

P.T.O. Confirmation No.: 1378

For. **SURFACE TREATING APPARATUS (AS AMENDED)**

INFORMATION DISCLOSURE STATEMENT AND STATEMENT PURSUANT TO 37 CFR 1.97(d)

Attn: Group Director

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

August 2, 2007

Sir:

The attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached Form PTO-1449. A copy of each non-U.S. Patent document is attached.

This Information Disclosure Statement is submitted after the mailing of a final action, a Notice of Allowance, or an action that otherwise closes prosecution in the application, but on or before payment of the Issue Fee.

The undersigned hereby certifies:

XX That each item of information contained in this Information Disclosure Statement was first cited in a communication from the European Patent Office in a counterpart application on June 4, 2007, not more than three months prior to the filing of this Information Disclosure Statement;

___ That no item of information contained in this statement was cited in a communication from a foreign patent office in a counterpart foreign application, and, to the knowledge of the undersigned after making reasonable inquiry, no information contained in this statement was known to any individual designated in 37 CFR § 1.56(c) more than three months prior to the filing of this statement.

The above information is presented so that the Patent and Trademark Office can determine any materiality thereof to the claimed invention. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the documents cited in the attached Form PTO-1449 be made of record therein and appear on the first page of any patent to issue therefrom.

Please charge the $180.00 fee required under 37 CFR § 1.17(p) to Deposit Account No. 01-2340.

Respectfully submitted,

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PATENT TRADEMARK OFFICE

Enclosures: PTO 1449; Copy of ESR dated June 4, 2007; References (9)

INFORMATION DISCLOSURE CITATION PTO-1449	Atty. Docket No. **000593B**	Serial No. **10/615,381**
	Applicant(s): **NISHIUCHI, et al.**	
	Filing Date: **July 9, 2003**	Group Art Unit: **1763**

U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA	4,581,113	Morimoto et al.	04-08-1986	204	192	
_____	AB	4,534,840	Shindo et al.	08-13-1985	204	192	
_____	AC	4,837,114	Hamada et al.	06-06-1989	427	127	
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_____	AE						

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		Document No.	Date	Country	Translation (Yes or No)
_____	AF	EP 0 104 916	04-04-1984	EPO	
_____	AG	EP 0 811 994	12-10-1997	EPO	
_____	AH				
_____	AI				
_____	AJ				

Examiner	Date Considered

INFORMATION DISCLOSURE CITATION PTO-1449	Atty. Docket No. **000593B**	Serial No. **10/615,381**
	Applicant(s): **NISHIUCHI, et al.**	
	Filing Date: **July 9, 2003**	Group Art Unit: **1763**

OTHER DOCUMENTS

_____	AK	Ahmed et al.: "ION VAPOUR DEPOSITION FOR CORROSION PROTECTION OF PERMANENT MAGNETS,"Modern Magnetic Materials, Conference Proceedings, June 20, 1989, pp. 8301-8309.
_____	AL	Dhere et al.: "PURITY AND MORPHOLOGY OF ALUMINUM FILMS," *Thin Solid Films*, Switzerland, Vol. 30, No. 2, December 1975, pp. 267-279.
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_____	AN	Wytenburg et al.: "Long-lived aluminum evaporation source for controlled, reproducible deposition of clean ultrathin films under ultrahigh vacuum conditions," *Journal of Vacuum Science & Technology: Part A*, Vol. 10, No. 6, November 1, 1992, New York, New York, pp. 3597-3598.
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_____	AP	Koiwa et al.: "DEHYDROGENATION OF VANADIUM BY ANNEALING WITH ZIRCONIUM FOILS," *Journal of the Less-Common Metals*, Vol. 72, No. 1, July 1980, Switzerland, pp. 125-132.
_____	AQ	Love et al.: "Thick deposits of ultrahigh-purity aluminum," *Journal of Vaccum Science and Technology*, Vol. 11, No. 6, USA, November 1974, pp. 1124-1127.

Examiner	Date Considered